In the Claims

1. (Previously Cancelled)

2. (Currently Amended) The apparatus according to claim 12, wherein the piezoelectric ~~piezoelectric~~ actuators are in a random distribution pattern ~~arbitrarily distributed over~~ on the surface between the carrier plate and the closure plate.

3. (Currently Amended) The apparatus according to claim 12 wherein the piezoelectric ~~piezoelectric~~ actuators are present on the surface between the carrier plate and the closure plate ~~distributed~~ as a function of ~~according to~~ a ~~desired~~ distribution of force over the surface between the carrier plate and closure the plate.

4. (Currently Amended) The apparatus according to claim 12, wherein the piezoelectric actuators ~~are~~ are of a type capable of being differentially triggered according to a desired distribution of force over the surface between the carrier plate and the closure plate.

5.. (Currently Amended) The apparatus according to claim 12, wherein the piezoelectric actuators are of a type capable of being triggered dynamically so as to match a dynamic behavior of the material to be pressed and/or the tools to be clamped.

6. (Currently Amended) ~~The~~ A process for making the apparatus according to claim 12, wherein ~~a~~ the number of piezoelectric actuators is determined ~~required, said number being derived~~ from a closing force and expansion of the apparatus required for generating a surface pressure.

7. (Previously Cancelled)

8. (Currently Amended) The apparatus according to claim 12, wherein the piezoelectric actuators are in a geometric pattern ~~provided in any desired geometry~~ which corresponds to ~~can be matched to any~~ machine requirements.

9. (Currently Amended) The apparatus according to claim 12, wherein the piezoelectric sensors are ~~provided~~ located between the closure plate and the carrier plate.

10. (Currently Amended) ~~The~~ A method of operating the apparatus according to claim 12, wherein during operation, a subset of the piezoelectric actuators are used as piezoelectric sensors.

11. (Currently Amended) The method ~~apparatus~~ according to claim 10, wherein the piezoelectric actuators that are employed as piezoelectric sensors, are employed only briefly as such sensors.

12. (Currently Amended) A pressure-generating apparatus comprising a stationary support plate, and a carrier plate traveling in relation thereto and capable of being fixed in working position, said carrier plate comprising on its side towards the support plate an electromechanically disengageable closure plate, wherein material to be pressed or tools to be clamped are arranged between the closure plate and the support plate, further wherein a ~~disengaging~~ force is triggered to disengage the closure plate by a number of piezoelectric actuators located on the carrier plate and the closure plate, and the closure plate is capable of being fixed in at least one piezo displacement intermediate position ~~which executes a piezo displacement,~~ from which intermediate position the carrier plate can be guided and subsequently fixed with the closure plate being disengaged by an additional piezo displacement.

13. (Previously Added) The apparatus according to claim 12 for use in an injection molding machine.

14. (Previously Added) The apparatus according to claim 2, wherein the piezoelectric actuators are distributed in a matrix.

15. (Currently Amended) The apparatus according to claim 8, wherein the piezoelectric actuators are ~~provided~~ in the shape of a rectangle.